

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5347-204			Serial No. not yet assigned
LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)				Applicants: Daniel J. C. Hill, et al.			J 1036 U.S. P. 09/781881 02/12/01
				Filing Date concurrently herewith			
U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
1		11-329944	11/30/99	IPO (Abstract in English)	H01L	21/027	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
2.	J.C.H. Spence et al, <u>Low Energy Point Reflection Electron Microscopy</u> , Surface Review and Letters, Vol 4, No. 3 (1997) pp 577-587.						
3.	J.C.H. Spence et al; <u>On the reconstruction of low voltage point projection holograms</u> , Electron Holography, (1995) pp 267-276.						
4.	Hans-Werner Fink et al; <u>State of the Art Low-Energy Electron Holography</u> , Electron Holography (1995) pp 257-266.						
5.	J.C.H. Spence et al; <u>Electron Holography at Low Energy</u> , Introduction to Electron Holography, pp 311-331.						
6.	D.C. Joy et al; <u>Advanced SEM Imaging</u> , Characterization and Metrology for ULSI Technology, 1998 International Conference, pp 653-666.						
7.	Russell Young et al; <u>The Topografiner: An Instrument for Measuring Surface Microtopography</u> , Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011.						
8.	Werner Veith et al; <u>Point Projector Electron Microscope</u> , Phys. Rev. Vol. 56, 705 (1939).						

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6/08/2001 JDS

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DATE CONSIDERED 1/27/03

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5347-204	Serial No. 09/781,881		
LIST OF DOCUMENTS CITED BY APPLICANT <i>Use several sheets if necessary</i>				RECEIVED JUN 14 2001			
				Applicants: Daniel J. C. Herr et al.	TO 1700		
				Filing Date February 12, 2001	Group 1645		
U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
<i>UV</i>	1	11-329944	<i>11/30/99</i>	JPO (Abstract in English)	H01L	21/027	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>UV</i>	2.	J.C.H. Spence et al; <i>Low Energy Point Reflection Electron Microscopy</i> . Surface Review and Letters, Vol. 4, No. 3 (1997) pp 577-587.					
<i>UV</i>	3.	J.C.H. Spence et al; <i>On the reconstruction of low voltage point projection holograms</i> , Electron Holography, (1995) pp 267-276.					
<i>UV</i>	4.	Hans-Werner Fink et al; <i>State of the Art Low-Energy Electron Holography</i> , Electron Holography (1995) pp 257-266.					
<i>UV</i>	5.	J.C.H. Spence et al; <i>Electron Holography at Low Energy</i> , Introduction to Electron Holography, pp 311-331.					
<i>UV</i>	6.	D.C. Joy et al; <i>Advanced SEM Imaging</i> , Characterization and Metrology for ULSI Technology; 1998 International Conference, pp 653-666.					
<i>AB</i>	7.	Russell Young et al; <i>The Topografiner: An Instrument for Measuring Surface Microtopography</i> , Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011.					
<i>UV</i>	8.	<i>G. Morton</i> Werner Veith et al; <i>Point Projector Electron Microscope</i> , Phy. Rev. Vol. 56, 705 (1939).					

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Sheet 1 of 1

Complete if Known

Application Number	09/781,881
Filing Date	February 12, 2001
First Named Inventor	Daniel J. C. Herr
Group Art Unit	1645
Examiner Name	not yet assigned
Attorney Docket Number	5347-204

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U. S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Class/Art
		Number	Kind Code (if known)				
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		Office	Number	Kind Code (if known)				
WW	2.		JP 09 016062A	A	Patent Abstracts of Japan	01/17/1997		

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	
WW	3.	E. Hecht: "Optics" 1987, Addison-Wesley XP002184727, page 593-596	
WW	4.	Anonymous: "Wafer Conformable Mask Image", Research Disclosure (December 1984) page 609 XP002184726.	
WW	5.	C. Jacobsen et al; "Projection X-Ray Lithography Using Computer-Generated Holograms: A study of compatibility with proximity lithography"; Journal of Vacuum Science and Technology: Part B, Am Inst. of Physics. New York, US vol. 10. No. 6 (11/1/1992) pgs 3177-3181 XP000332529	
WW	6.	C. Jacobsen et al; "X-Ray Holographic Microscopy Using Photoresists", Journal of the Optical Society of America - A, Optical Society of America, Wash. US. vol. 7, no 10 (10/1/1990) pgs 1847-1861 XP000163095.	

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TC 1700

Examiner Signature	<i>Daniel J. C. Herr</i>	Date Considered	<i>1/27/03</i>
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